

<b>Notice of References Cited</b>	Application/Control No. 09/970,100	Applicant(s)/Patent Under Reexamination AGARWAL ET AL.	
	Examiner William P. Fletcher III	Art Unit 1762	Page 1 of 1

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#### NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Definition of "resin" from Merriam-Webster's Collegiate Dictionary, 10th Edition, © 1999 by Merriam-Webster, Inc., page 996.
	V	Definition of "ceramic" from Hawley's Condensed Chemical Dictionary, 12th Edition, © 1993 by Van Nostrand Reinhold, page 240.
	W	Pierson, H. O., "Handbook of Chemical Vapor Deposition (CVD)," © 1992 by Hugh O. Pierson, pages 225, 226, 231-234, 236-240.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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